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# Room Temperature 2D Memristive Transistor with Optical Short-term Plasticity

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*Abstract*—Memristive devices with short-term plasticity (STP), gate tunability, site controllability, and light sensitivity have generated significant interest for wide range of applications, especially mimicking the neural network. However, there is still no memristive device that can accomplish all those goals in tandem at room temperature. To fill that void, in this work, 1T-phase quantum dot superlattice is created on 2H-phase monolayer single crystal molybdenum disulfide (MoS<sub>2</sub>) back-gated field-effect transistor by focused electron beam irradiation. The quantum dots work as charge traps that induce memristive resistance. The memristive resistance can be controlled by applying gate bias and shows STP to light stimulation. Thus, this work demonstrates the first room temperature light sensitive memristive transistor that can serve as artificial retina device for artificial intelligence, and memristive receiver for optical-electrical neuromorphic interface.

### I. INTRODUCTION

Memristive devices are promising artificial neuron devices for neuromorphic computing and machine learning [1], [2]. Memristive devices that have short-term plasticity (STP, where the memory spontaneously decays after stimulation) are being pursued to mimic the synaptic connection [3]. Z. Wang et al. used diffusive Ag-inoxide memristive device to create STP [4]. However, this technique can only be applied to two terminal devices. Multiple terminal memristive devices or memristive transistors can bring a wider range of applications [5], [6]. However, those memristive transistors are based on random grain boundaries where the site is not controllable, and therefore not practical for large-scale integrated circuits. On the other hand, the biggest applications of neuromorphic computing are image processing and recognition, i.e., the "eyes" of artificial intelligence [7], [8]. For human eyes, the neurons are not only light sensing devices but also assemble an image processor [9], [10]. However, all the crossbar memristive devices, in principle, cannot respond to light stimulation. P. Maier et al. created an electro-photosensitive memristive device with InAs quantum dot array on twodimensional electron gas based on GaAs/AlGaAs heterostructure [11], [12]. The quantum dots trap charges and decay with light stimulation and carrier flow, which mimics the working principle of the retina rod cell as illustrated in Fig. 1a. However, this device only works in cryogenic low temperature. In this work, we report a memristive transistor based on precisely designed quantum dot superlattice on single crystal monolayer MoS<sub>2</sub> that is controllable with gate, works at room temperature and shows a memristive STP to light stimulation. The advantages of this device are summarized in Table 1.

#### II. MATERIAL PREPARATION

The MoS<sub>2</sub> atomic layers are synthesized via chemical vapor deposition method (CVD) by using sulfur (S) and molybdenum oxide (MoO<sub>3</sub>) powder as the precursors on Si/SiO<sub>2</sub> substrate. We perform the focused electron beam (FEB) irradiation on the monolayer MoS<sub>2</sub> with FEI XL-30 SIRION Scanning Electron Microscope (SEM) with Nanometer Pattern Generation System (NPGS) to manipulate the electron beam. The electron beam voltage is 30 kV, and the beam current is 580 pA with 2.1 nm spot size. As illustrated in Fig. 1b, the quantum dots are postioned in a square superlattice with 6.68 nm distance, and the size of the quantum dot is controlled by the point dose [13]. The fabricated device is shown in Fig. 1c. The gate dielectric is 285 nm SiO<sub>2</sub> with highly n-doped silicon substrate as backgate. The contact electrodes are made of 10/100 nm Ti/Au. The AFM measurement (Fig. 2a) indicates that the MoS<sub>2</sub> film is uniform and monolayer. Fig. 2b is the Kelvin Probe Force Microscopy (KPFM) measurement of the same region, where the FEB irradiated  $MoS_2$  shows larger contact potential difference ( $V_{CPD}$ ) compared to pristine MoS<sub>2</sub>, which implies larger work function. As shown in Fig. 3a and Fig. 3b, the FEB irradiated MoS<sub>2</sub> shows larger selected area electron diffraction (SAED) peak wavenumber, and exhibits three new peaks in Raman spectrum [14]-[17]. All those evidences point to the existence of 1T-phase (metallic) MoS<sub>2</sub>. Fig. 3c shows that the new PL peak emerges from the FEB irradiated MoS<sub>2</sub>, due to the creation of 1T-phase quantum dots in 2H-phase (semiconducting) MoS<sub>2</sub>. As shown in **Fig. 1c**, five devices are fabricated on the same MoS<sub>2</sub> grain with different FEB point doses of 28.6 fC, 114.3 fC, 228.7 fC, 457.4 fC, respectively, in addition to a pristine device. All the subsequent electrical measurements are conducted in  $4.2 \times 10^{-5}$ mBar vacuum. As shown in Fig. 4a and Fig. 4b, the FEB irradiated transistors show larger threshold voltage  $(V_T)$ . The work function change and  $V_T$  shift are illustrated in Fig. 4c. The 2H-phase MoS<sub>2</sub> is originally an n-type doped semiconductor. The FEB irradiated regions transform from semiconducting 2H-phase MoS<sub>2</sub> to metallic 1T-phase MoS<sub>2</sub>. The metallic quantum dots attract abundant electrons in the conduction band of adjacent 2H-phase to fill the ground state energy level of the quantum dots. As a result, the conduction band of 2H-phase MoS<sub>2</sub> has less electrons and the Fermi level moves towards the valance band. As the irradiation dose increases, the quantum dot size increases. For larger quantum dots, the ground state energy of electrons (holes) has smaller (larger) energy, so the material's work function increases and the  $V_T$  increases.

#### **III. MEMRISTIVE RESPONSE**

Four probe measurement is carried out to extract the resistance of FEB irradiated MoS<sub>2</sub> excluding the contact resistance by measuring the sense voltage ( $V_{ds}$ ) on  $V_{ds}$  electrodes with force voltage ( $V_f$ ) and current (I) applied on  $V_f$  electrodes (**Fig. 1b**). The device is first measured with different  $V_f$  ranges without applying gate bias. As shown in **Fig. 5a** and **Fig. 5b**, the  $V_{ds}$  exhibits a hysteresis w.r.t sweeping forward and sweeping backward. As the  $V_f$  sweeping range increases from 1 V to 80 V, the hysteresis or memristive loop expands. The main mechanism controlling the hysteresis is the trapping and de-trapping of charges. There are two factors: Factor 1, as the  $V_f$  increases, the Fermi level moves down and trapped holes increase, which increases the resistance. Factor 2, as the current flows, the trapped holes decrease by recombining with mobile electrons, which reduces the resistance. When the  $V_f$  sweeps from negative to zero, the electrons are trapped near the "D" electrode as

illustrated in Fig. 5d. When the  $V_f = 0$  V, as illustrated in Fig. 5e, the trapped electrons are detected as residual  $V_{ds}$  as marked with blue dots in Fig. 5a and Fig. 5b. When the  $V_f$  sweeps from zero to a positive value, the quantum dots near the "D" electrode are charged with holes. The trapped holes reduce the Fermi level as illustrated in Fig. 5f. Factor 1 is saturated when all the traps are filled with holes, while the factor 2 increases as the current increases along with  $V_{f}$ . So the resistance reaches a saturation and starts to decrease at high  $V_f$  as shown in the inset of Fig. 5c. This is more significant when more electrons are generated by light as shown in Fig 6b. When the  $V_f$ sweeps from positive to zero, trapped holes in factor 1 decreases, and the factor 2 further reduces the holes. So the resistance decreases faster while sweeping backward and doesn't overlap with the resistance curve while sweeping forward. When  $V_f = 0$  V while sweeping backward, as illustrated in Fig. 5f, the residual trapped electrons and holes is also detected as residual voltage as marked with orange dots in Fig. 5a and Fig. 5b. The number of trapped charges decaying with time can generally be formulated as n = $Ne^{-\alpha t}$ , where N is the total number of the trapped charges and  $\alpha$  is the decay coefficient. The trapped charges generally decay faster at higher temperatures, which implies larger  $\alpha$ . In the case of quantum dot based memristive device in previous works [11], [12], only few quantum dots are created. Hence, those devices require cryogenic low temperature to maintain memristive behavior. In our case, the quantum dots are closely positioned in a square superlattice with 6.68 nm distance, which implies large N. Moreover, the monolayer 2D materials (in our case MoS<sub>2</sub>) are extremely sensitive to the trapped charges [18], [19]. That's the reason why our quantum dot based memristive device exhibits memristive behavior even at room temperature. As demonstrated in Fig. 5a, this memristive device can work at very low voltages, which can dramatically reduce the power consumption. In this case, the  $V_{ds}$  can be as low as 10<sup>-4</sup> V for a 2.1  $\mu m$  channel. Reducing the channel length can further reduce the voltage requirements. In order to better visualize the memristive behavior, we still choose 80 V as the  $V_f$  sweeping range in the subsequent measurements.

#### **IV. LIGHT RESPONSE**

Another interesting property of this memristive device is the gate tunability and light responsiveness. The measurement is conducted with light (halogen light) ON and OFF under different back gate voltages (V<sub>G</sub>). The resistance R is extracted by calculating  $V_{ds}/I$  as shown in Fig. 6a and Fig. 6b. The MoS2 is natively n-type doped with a threshold voltage of 20 V. When  $V_G > 20$  V, all the quantum dots are charged with electrons as illustrated in Fig. 6c, so the R doesn't have a memristive loop. When the light is ON, the lightinduced electrons and holes fill up all the quantum dots. Thus, the memristive response is also suppressed as illustrated in Fig. 6d. When the  $V_G$  is largely negatively biased, the memristive response starts to emerge even with the light ON.

The interesting response to light stimulation is further examined with modulating light illumination during the  $V_f$  sweeping as shown in Fig. 7. The  $V_f$  sweeps from -80 V to 80 V to -80 V with no gate bias. The light is mechanically blocked to switch OFF. In Fig. 7a and **Fig.** 7b, during the  $V_f$  sweeping, the *R* exhibits gradually rising peaks when the light is OFF. When the light is ON, the R exponentially decreases and progresses to a stationary value that is in between the light-always-on and light-always-off data. In other words, the device shows memristive response to  $V_f$  sweeping and STP to the light stimulation. This can be explained as shown in Fig. 7c. The main factor which increases the R is the trapped holes that move the local Fermi level towards lower energy. The main factors that decrease Rare the light generated electrons and the recombination of trapped holes with electrons. When the  $V_f$  is supplying positive voltage, the

holes are constantly generated near the "S" electrode. When the light is ON, the electrons and holes are generated by light, which leads to low R. When switching to light-OFF, electrons and holes recombine and some holes are trapped, and the increasing of  $V_f$  further increases the trapped holes, which gradually increases the resistance. When switching to light ON, the electron and holes are generated, and the trapped holes recombine with mobile electrons. This process reduces the resistance, which is the origin of STP. When  $V_f = 80$  V, the device reaches a resistance that is larger than the light-always-on condition and smaller than the light-always-off condition. In other words, the device "remembers" the history of the light stimulation.

#### V. SUMMARY

A room temperature light memristive transistor is created on monolayer single crystal MoS<sub>2</sub>. This is achieved by creating a 1Tphase MoS<sub>2</sub> quantum dot superlattice on 2H-phase MoS<sub>2</sub> using FEB irradiation. As the FEB irradiation dose increases, the material's work function increases, and the transistor's threshold voltage moves to larger values. Four probe measurements confirm that the transistor exhibits a memristive resistance corresponding to drain voltage sweeping and STP to light stimulation. Thus, this work demonstrates the first room temperature light sensitive memristive 2D-channel transistor that can serve as artificial retinal device for artificial intelligence, and memristive receiver for optical-electrical neuromorphic interface.

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**Fig. 1. (a)** The sketch shows the working principle of retina rode cell that accumulates charges with light stimulation and reduces the charges in dark. **(b)** The schematic on the bottom shows the device structure with MoS<sub>2</sub> as channel, Ti/Au as contacts, SiO<sub>2</sub> as back dielectric and Si as backgate. The focused electron beam (FEB) creates local 1T-phase regions in 2H-phase MoS<sub>2</sub>, which work as quantum wells in MoS<sub>2</sub> channel. As shown by the middle inset, the 1T regions grow in triangle shape due to the hexagonal lattice of MoS<sub>2</sub>. The top inset shows the band diagram of the superlattice, where the 2H ( $E_g = 1.8 \text{ eV}$ ) and 1T ( $E_g = 0 \text{ eV}$ )-phases are alternated. With light stimulation, the quantum well can trap electrons. In the dark, the trapped electron decays in the quantum wells formed by 1T dots. **(c)** The optical image of five backgated field effect transistors (FETs) fabricated on monolayer (1L) single crystal MoS<sub>2</sub> grown by chemical vapor deposition (CVD). The FET channels are the FEB irradiated regions marked with bracket and corresponding irradiation point dose (in unit of fC) on the right side. The inset is the schematic of the 1T-phase MoS<sub>2</sub> quantum dots created by FEB irradiation in 2H-phase MoS<sub>2</sub>.  $V_f$  and  $V_{ds}$  mark the electrodes for force voltage and sense voltage for four-probe measurement, respectively. The white scale bar is 10 um.



Fig. 2. **(a)** Atomic force microscope (AFM) image of the  $MoS_2$  sample. The inset is the cross-section plot of the AFM data along the red dashed line. The average thickness of ~0.65 nm indicates monolayer. (b) Kelvin probe force microscopy (KPFM) image of the same region as in (a). Higher contact potential difference  $(V_{CPD})$ implies larger work function. As FEB irradiation the dose increases, the work function of MoS<sub>2</sub> increases.



**Fig. 3.** (a) SAED measurement showing that FEB irradiated  $MoS_2$ 's peaks have larger wavenumber, which is an indication of 1T phase  $MoS_2$ . (b) Raman spectrum showing the FEB irradiated  $MoS_2$  has new peaks at 151.58 cm<sup>-1</sup>, 227.99 cm<sup>-1</sup>, and 305.2 cm<sup>-1</sup>, which is a signature of 1T phase  $MoS_2$ . (c) PL measurement reveal the new PL peak emerge from FEB irradiated  $MoS_2$ , which can be attributed to the creation of 1T-phase quantum dots in 2H-phase  $MoS_2$ .



**Fig. 4. (a)** Drain current ( $I_D$ ) vs. back gate voltage ( $V_G$ ) curve for MoS<sub>2</sub> FETs with different irradiation doses. **(b)** The normalized  $I_D$  -  $V_G$  curve for comparing the threshold voltage ( $V_T$ ). The inset shows the extracted  $V_T$ . As the irradiation dose increases, the  $V_T$  increases. **(c)** The top and bottom sketches represent the band diagrams with small and large quantum dots, respectively. As the irradiation dose increases. For superlattice with larger quantum dots, the ground state energy of electrons (holes) has smaller (larger) energy, so the work function increases and the  $V_T$  increases.



**Fig. 5.** FEB irradiated transistor characterization. (a), (b)  $abs(V_{ds}) vs. V_f$  with different  $V_f$  sweeping range. The red line is the data for  $V_f$  sweeping forward from – to +. The black line is the data for  $V_f$  sweeping backward from + to –. The dashed lines are data with negative value. The blue and orange dots mark the data when the  $V_f = 0$  V for  $V_f$  sweeping forward and backward, respectively. (c) The resistance (*R*) vs.  $V_f$ . To better visualize the result, the data is calculated with  $R \times 10^{[\max(V_f)-10]/2}$  to separate the data in vertical direction for different  $V_f$  sweeping range. (d), (e), (f), (g) illustrate the working principle. As the  $V_f$  increases, the Fermi level moves down and trapped holes increase, which increases the resistance. As the current flows, the trapped holes decrease by recombining with mobile electrons, which reduce the resistance.





**Fig. 6.** Measurements demonstrating the gate tunability and light sensitivity. (a) *I vs.*  $V_f$  with different back gate voltage ( $V_G$ ) with light ON. (b) *I vs.*  $V_f$  with different  $V_G$  with light OFF. To better visualize the result, the data in (a) and (b) are calculated with  $R \times 10^{(30-V_G)/2.5}$  to separate the plot in vertical direction for different  $V_G$ . The memristive response can be reduced with applying positive gate voltage or light stimulation. (c) When the  $V_G > V_T$ , the quantum dots are filled with electrons, which eliminate the memristive loop. (d) When the light is constantly on, the quantum dots are also filled with electrons, which eliminate the memristive loop. alarger gate voltage reduces the electrons.

**Fig.** 7. Light response. (a) The absolute value of *I* in log scale and  $V_{ds}$  as the function of  $V_f$  for light modulated condition with no gate bias. The light OFF regions are marked in (b). (b) The *R* as the function of  $V_f$  for light always ON, light always OFF, and light modulated condition, where the resistance for light modulated condition is calculated from (a). The gray regions are when the light is OFF for light modulated condition. (c) The memristive loop is due to hole generation during the light OFF. The optical short-term plasticity is due to the hole recombination during the light ON.

 Table 1. The advantages of this work compared to previous studies.

	Refs. (3)(4)	Refs. (5)(6)	Refs. (7)(8)	This Work
STP	$\checkmark$			√
Gate tunability		$\checkmark$		$\checkmark$
Site controllability	$\checkmark$		$\checkmark$	√
Light sensitivity			$\checkmark$	√
Room temperature operation	$\checkmark$	$\checkmark$		√